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Attorney Docket SEL 191

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re Application of )  
 )  
Tanaka et al. )  
 )  
Serial No.: 09/610,637 )  
 )  
Filed: July 5, 2000 )  
 )  
For: Laser Irradiation Apparatus, Laser )  
Irradiation Method, Semiconductor )  
Device And Method Of Manufacturing )  
A Semiconductor Device )  
 )  
Art Unit: 2813 )  
 )  
Examiner: David S. Blum )

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:  
Commissioner for Patents ,  
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Name of applicant, assignee, or Registered Rep.  
Shannon Wallace 2/11/05  
Signature Date

Commissioner for Patents  
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**AMENDMENT C (AFTER FINAL)**

Sir:

In response to the Final Rejection of October 13, 2004, a one month extension of time being submitted herewith, please enter the following amendment in the above-identified application: